

## Electronic Patent Application Fee Transmittal

<b>Application Number:</b>	10511883			
<b>Filing Date:</b>	19-Oct-2004			
<b>Title of Invention:</b>	Apparatus and method for depositing thin film on wafer using remote plasma			
<b>First Named Inventor/Applicant Name:</b>	Young Hoon Park			
<b>Filer:</b>	James J. Merrick/Jessika Holmes			
<b>Attorney Docket Number:</b>	YPL-0108			
Filed as Large Entity				
<b>U.S. National Stage under 35 USC 371 Filing Fees</b>				
Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
<b>Basic Filing:</b>				
<b>Pages:</b>				
<b>Claims:</b>				
<b>Miscellaneous-Filing:</b>				
<b>Petition:</b>				
<b>Patent-Appeals-and-Interference:</b>				
<b>Post-Allowance-and-Post-Issuance:</b>				
<b>Extension-of-Time:</b>				

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Miscellaneous:				
Request for continued examination	1801	1	810	810
Total in USD (\$)				810